

Radiation tolerance of a 0.13 μm commercial CMOS technology

F.Faccio, G.Anelli, S.Baldi, S.Bonacini, G.Cervelli,
J.Christiansen, M.Despeisse, K.Hänsler,
K.Kloukinas, A.Marchioro, P.Moreira, R.Szczygiel

Introduction

- With our resources, long cycles from early development to technology use
- Technologies are getting more complicated... and expensive
- Need to start ahead of time, and group more users

Cycle for quarter micron

1996	First discussions and measurements
1997	Proposal RD49 “Radtol”, measurements on 5 technologies
1998	First design: “DEEP1”
1999	First MPW1
2000	First dedicated engineering runs

Outline

- Technology choice
- Test structures
- TID results
- SEE results
- Conclusion (for the time being...)

Technology choice

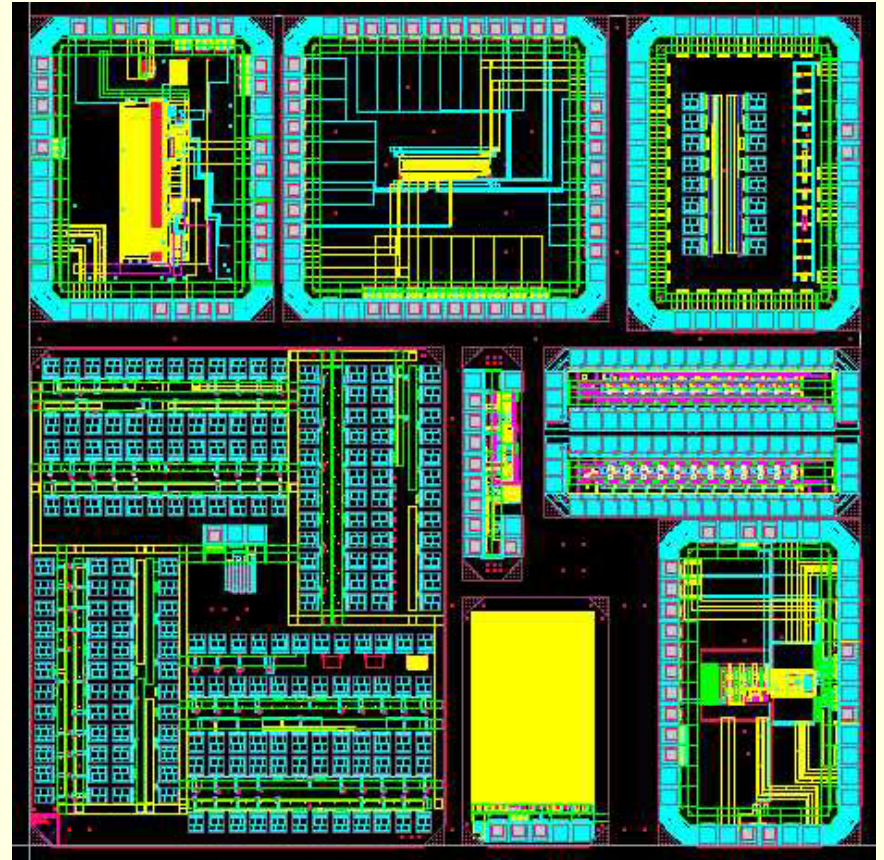
- Skip 0.18 μm – already peak production
- Next wave: 0.13 μm technology node
- Features of the chosen technology:
 - All-copper technology
 - Vdd=1.2-1.5 V
 - Triple gate oxide
 - Min lithographic image 0.11 μm
 - 4 to 8 metal levels (options on stack)
 - Planarization and interlevel dielectrics with low-k
- Device options:
 - Standard, High and Low Vt NMOS and PMOS, ZeroVt NMOS
 - Ultra-thin gate oxide NMOS and PMOS
 - Thick oxide (2.5 V) NMOS and PMOS, ZeroVt NMOS
 - n+, p+ and pc resistors
 - Metal-Metal capacitors

Test structures

- Wafer with macros from foundry (received 1/02, hardware 01)
- SRAM from foundry for SEEs (received 10/01)
- Design of 5x5 mm² module in Foundry MPW, with RAL and Imperial College (submitted 11/02, received 3/03):
 - Individual transistors of all types (enclosed, linear)
 - Individual transistors for noise measurements
 - Resistors & Diodes
 - FoxFETs
 - Shift register for SEEs
 - Circuit building blocks (TDC, Fast serializer for optical digital transmission, bandgap, FEAmplifier, SRAM)

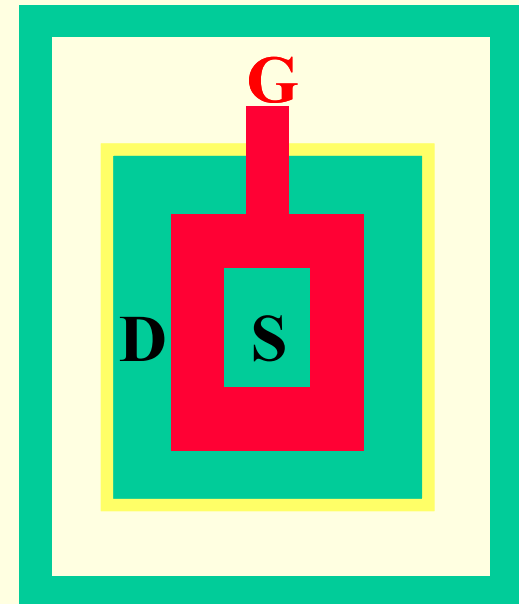
“CuTel1” module

- Run options:
 - 6 levels of metal (4 thin; 2 thick)
 - Mimcap
 - Op resistors
 - All transistors (all Vts, all oxide thicknesses)



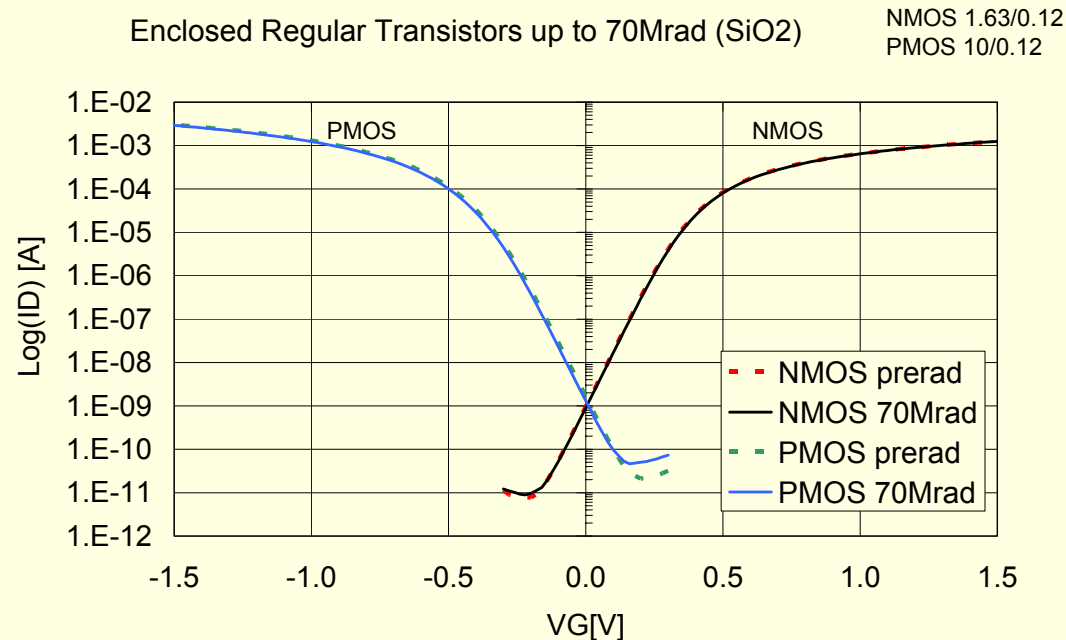
TID results

- Chapters:
 - Enclosed transistors
 - Large linear transistors, $W=10\mu\text{m}$
 - Narrow linear transistors, minimum W



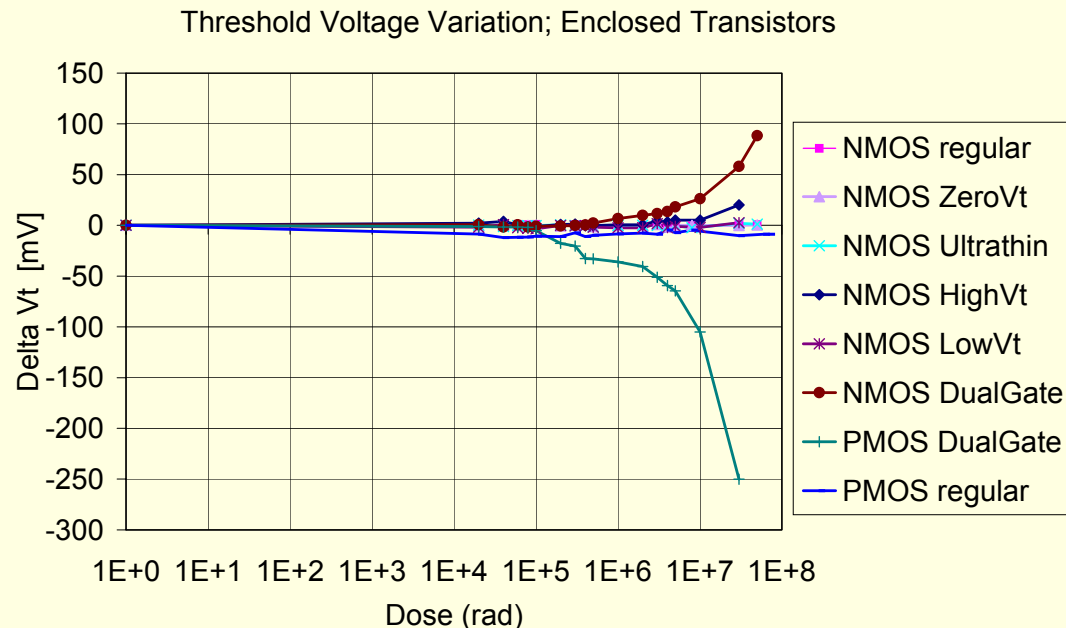
TID results: enclosed transistors

- All TID irradiations with X-rays
- Negligible degradation for all thin-oxide enclosed transistors (NMOS and PMOS), for all parameters



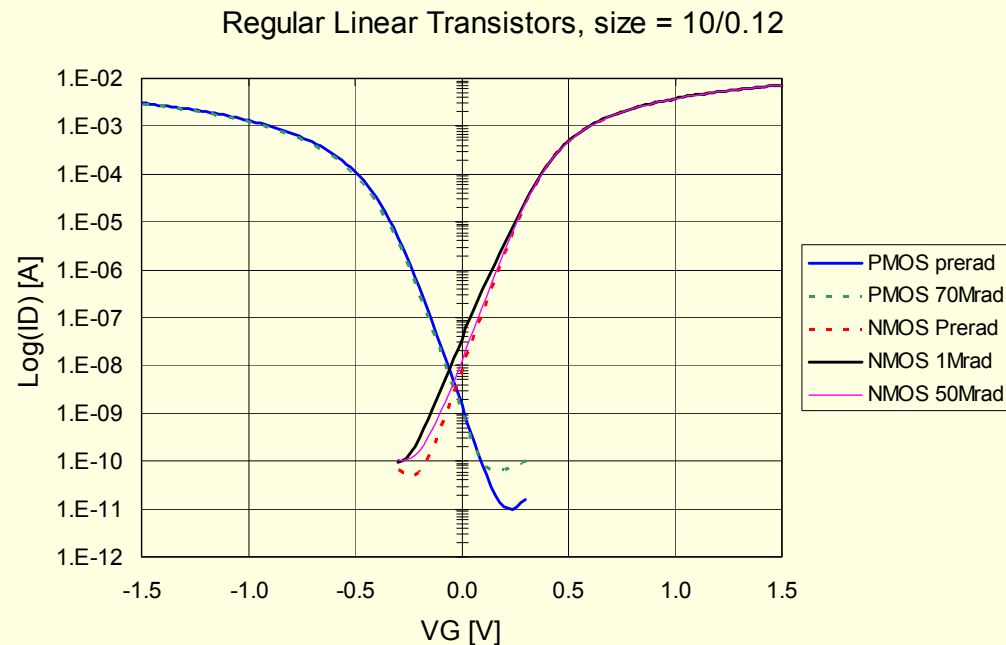
TID results: enclosed transistors

- $W=10\mu\text{m}$, $L = \text{min size}$:
 - Standard, HighVt, LowVt, Ultrathin = $0.12\mu\text{m}$
 - DualGate = $0.26\mu\text{m}$; ZeroVt = $0.42\mu\text{m}$



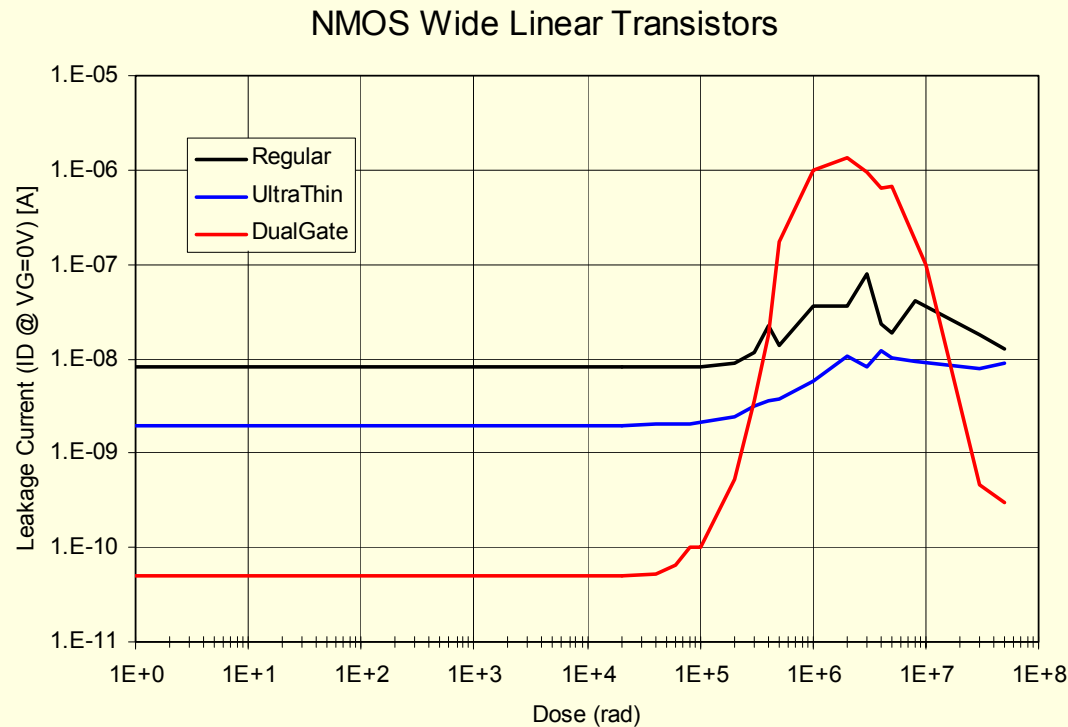
TID results: wide linear transistors

- ΔV_t comparable to enclosed transistors
- PMOS overall comparable to enclosed transistors
- NMOS: edge effect (SMALL!!)



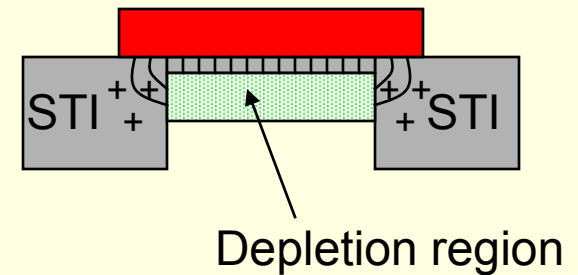
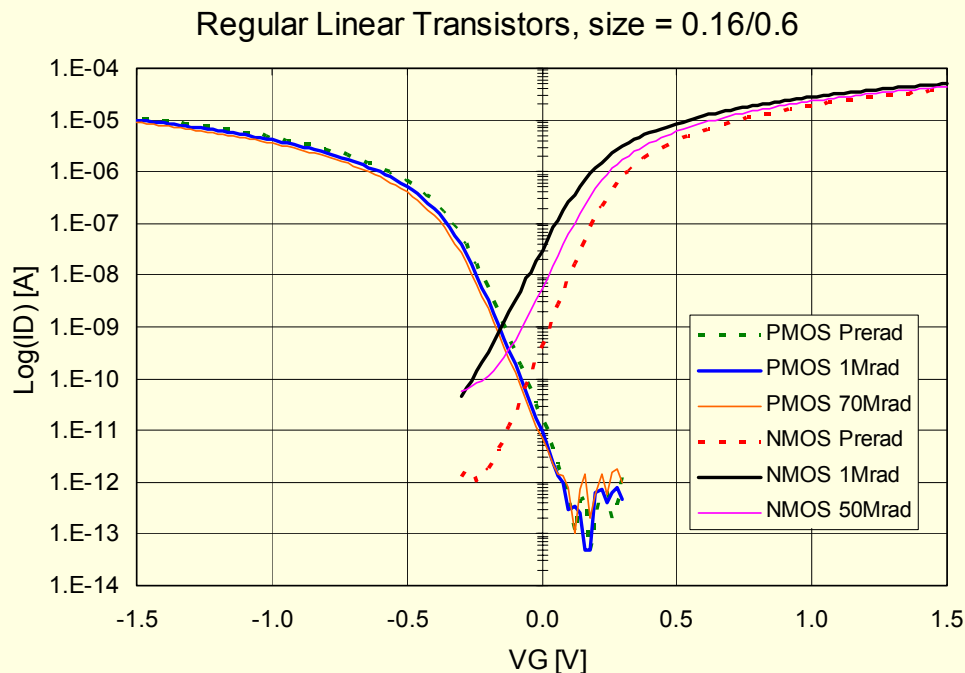
TID results: wide linear transistors

- Leakage current changes with dose: peak at 1-5Mrad



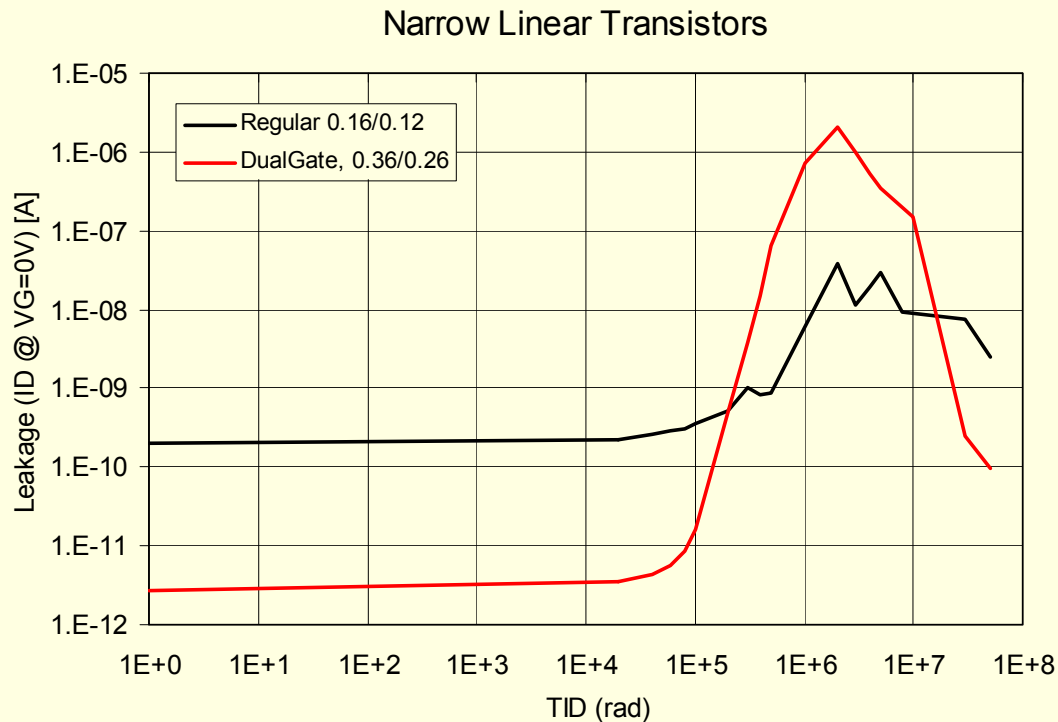
TID results: narrow linear transistors

- Change in V_t and subthreshold slope, hence leakage
- Strong edge effect: Narrow Channel Effect
- All transistor types affected



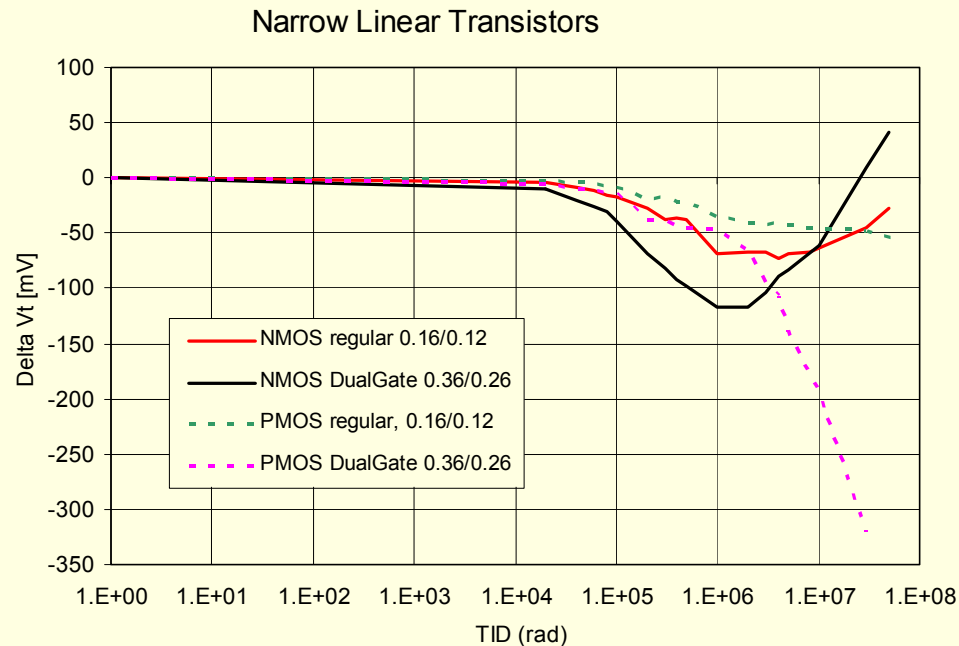
TID results: narrow linear transistors

- Leakage current changes with dose: peak at 1-3Mrad



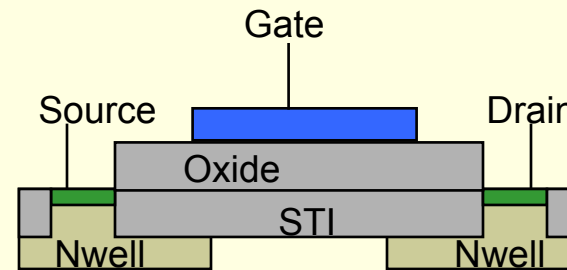
TID results: narrow linear transistors

- Threshold voltage shift not negligible – especially for Dual Gate
- Peak in degradation for NMOS at 1-5Mrad

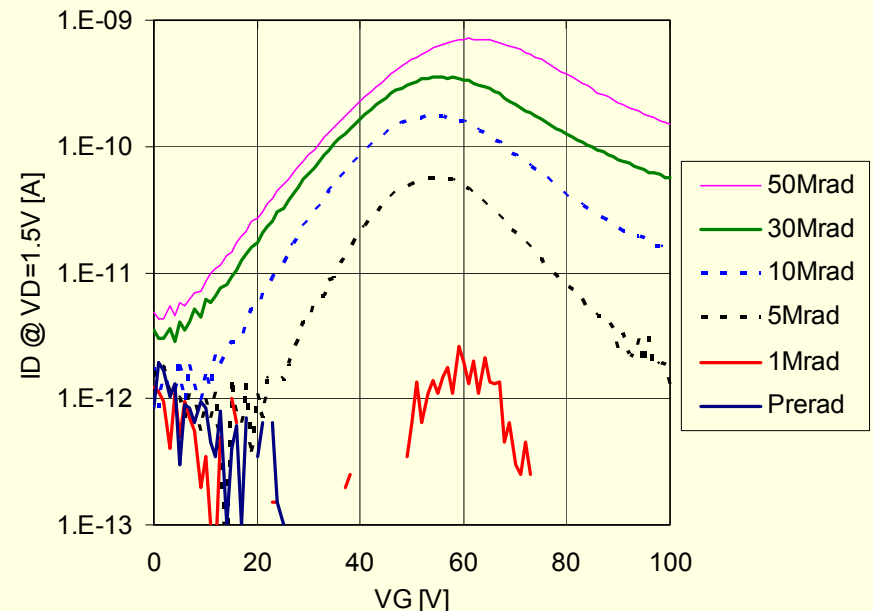


TID results: FOXFETs

- Transistors on Field Oxide
- PC or M1 “gate”
- N+ diffusion or Nwell Source & Drain
- Only Nwell-Nwell has some current (at voltages well above V_{dd}!)



NWell FOXFET, size 5/0.92

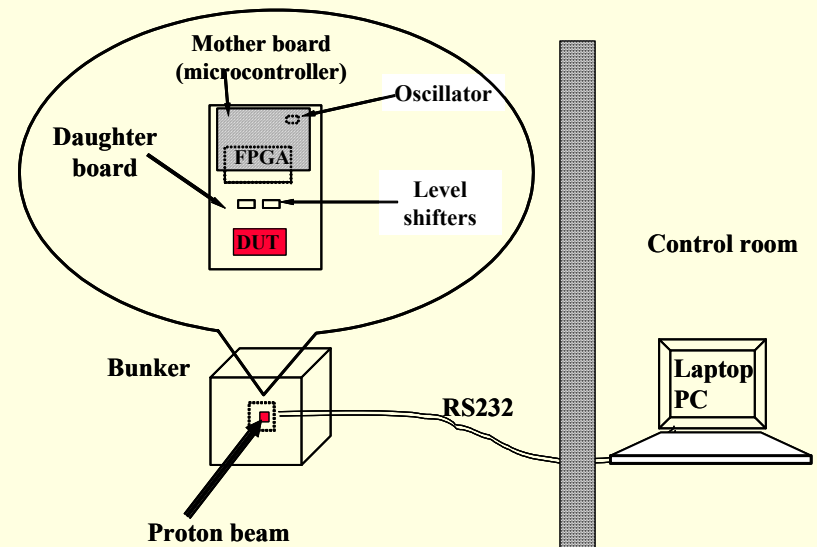


TID results: summary

- Enclosed transistors are very good, as expected (very thin gate oxide)
- DualGate transistors (for I/Os and analog at 2.5V) have to be used carefully – V_t shift is not negligible at high doses
- Large linear transistors look very good also for vast majority of applications
- Narrow linear transistors are more sensitive
- From FOXFETs, lateral isolation is not a problem
- Where is the “border” between narrow and large channels?
- Annealing effects to be studied in more detail

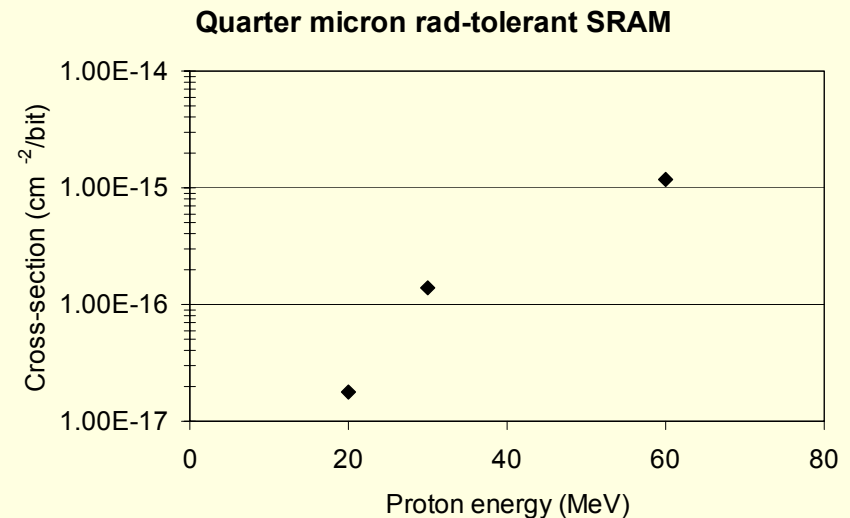
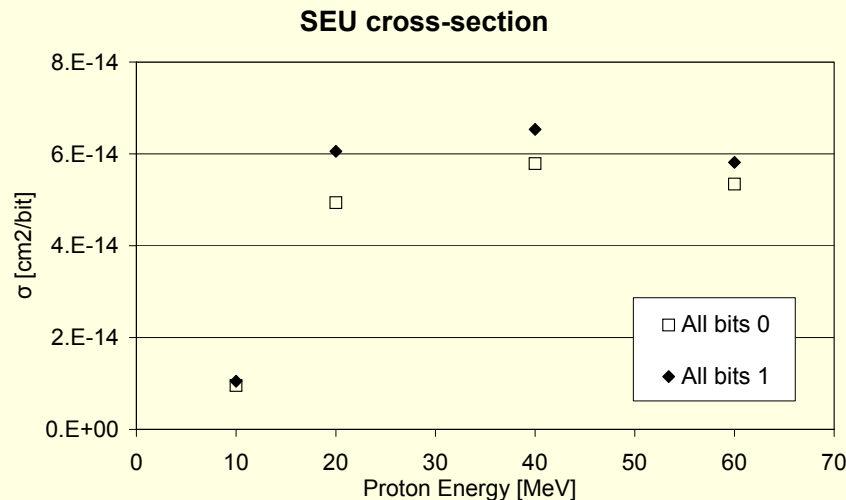
SEEs on SRAM

- 16k x 16 SRAM design from Foundry (linear transistors)
- Irradiation at PSI: up to 60MeV protons
- Flux: $1-4 \times 10^8$ p/cm²s
- Proton energy 10, 20, 40 and 60 MeV
- 2 patterns: all-1 and all-0
- SEL detection active at all times
- V_{dd} = 1.5V and 1.25V



SEEs on SRAM

- Equivalent TID of 260 krad (Si)
- No SEL detected
- σ increases by 20-30% for TID of about 90 krad
- σ increases by 20-30% for lower power supply (1.25V)



Conclusion (for the time being...)

■ TID

- Enclosed transistors are very good
- No guardring needed
- Linear transistors look very promising, details still to be studied (annealing, narrow channel effects)
- DualGate are more sensitive: careful use

■ SEEs

- Sensitive charge smaller, higher SEU sensitivity
- NB: without enclosed transistors, error rates can be considerably higher than for present 0.25 μ m designs
- SEL not observed and not expected to be a crucial issue for our applications (careful: design-dependent sensitivity)